

REMARKS/ARGUMENTS:

Claim 2 is canceled without prejudice. Claims 1, 4, and 16 are amended. Claims 1 and 3-32 are pending in the application. Reexamination and reconsideration of the application, as amended, are respectfully requested.

The present invention relates to a pressure sensor device to be used for monitoring an air pressure in a tire, which detects pressure fluctuations of gas or liquid and transmits electrical signals. (Applicant's specification, at p. 1, lines 4-7).

CLAIM REJECTIONS UNDER 35 U.S.C. § 102:

Claims 1-32 stand rejected under 35 U.S.C. § 102(b) as being anticipated by Shibasaki et al. (U.S. Patent No. 5,453,727). This rejection is moot with respect to claim 2 due to the cancellation of this claim. The Applicant respectfully traverses this rejection as to claims 1 and 3-32. Claim 1, as amended, is as follows:

A pressure sensor device comprising:

a supporting substrate;

a sensor substrate made of a piezoelectric material, having a lower surface on which a sensor section formed of a surface acoustic wave element for detecting pressure is formed; and

a sealing member that is joined to an upper surface of the supporting substrate and the lower surface of the sensor substrate and forms a sealing space for sealing the sensor section between the substrates.

Applicant respectfully submits that Shibasaki cannot anticipate or render obvious claim 1, because Shibasaki fails to teach or suggest "a sensor substrate made of a piezoelectric material, having a lower surface on which a sensor section formed of a surface acoustic wave element for detecting pressure is formed."

Shibasaki teaches a semiconductor sensor of substrate 1, a compound semiconductor layer 2, a sensor layer 3 with a semiconductor sensor and an electrode 17 (Shibasaki, column 8, lines 40-46; Figure 15A).

In contrast, the present invention uses a surface acoustic wave element provided on a piezoelectric substrate. Amended claim 1 requires that the sensor substrate be made of a piezoelectric material and that the sensor section be formed of a surface acoustic wave element. These limitations are neither taught nor suggested by Shibasaki.

In addition, Applicant respectfully disagrees with the Office's assertion at p. 3 of the Office Action that Shibasaki teaches "a sealing space for sealing the sensor section between the substrates (col. 6, lines 1 to 10)." Applicant believes that Shibasaki only teaches the second and the third compound semiconductor layers that provide a protective effect against oxidation in air and damage by passivation. Shibasaki fails to teach or suggest the sealing space of the present invention.

In light of the foregoing, Applicant respectfully submits that Shibasaki could not have anticipated or rendered claim 1 obvious, because Shibasaki fails to teach or suggest each and every claim limitation. Claims 3-32 depend from claim 1 and cannot be anticipated or rendered obvious for at least the same reasons as claim 1. Withdrawal of this rejection is thus respectfully requested.

In view of the foregoing, it is respectfully submitted that the application is in condition for allowance. Reexamination and reconsideration of the application, as amended, are requested.

If for any reason the Examiner finds the application other than in condition for allowance, the Examiner is requested to call the undersigned attorney at the Los Angeles, California telephone number (310) 785-4600 to discuss the steps necessary for placing the application in condition for allowance.

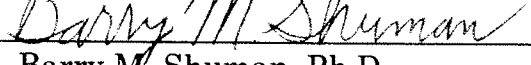
Appl. No. 10/580,633
Amdt. Dated September 12, 2007
Reply to Office Action of June 14, 2007

Attorney Docket No. 81872.0114
Customer No.: 26021

If there are any fees due in connection with the filing of this response, please charge the fees to our Deposit Account No. 50-1314.

Respectfully submitted,
HOGAN & HARTSON L.L.P.

Date: September 12, 2007

By: 
Barry M. Shuman, Ph.D.
Registration No. 50,220

1999 Avenue of the Stars, Suite 1400
Los Angeles, California 90067
Phone: 310-785-4600
Fax: 310-785-4601